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REPLY UNDER 37 C.F.R. § 1.116 EXPEDITED PROCEDURE **EXAMINING GROUP 1762**

> PATENT 0397-0404P

IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: H. TAKEUCHI et al.

Conf.: 4024

Appl. No.:

09/541,089

Group: 1762

Filed:

March 31, 2000

Examiner: M. PADGETT

For:

PLASMA PROCESSING METHOD

LARGE ENTITY TRANSMITTAL FORM FOR REPLY AFTER FINAL UNDER 37 C.F.R. § 1.116

Assistant Commissioner for Pa Washington, DC 20231	atents February 6, 2003
Sir:	
Transmitted herewith is application.	a reply in the above-identified
The enclosed document is of Mailing provisions of	being transmitted via the Certificate 37 C.F.R. § 1.8.
☐ The enclosed document is	s being transmitted via facsimile.
The fee has been calculated a	as shown below:

	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR		PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL	8	-	20	=	0	\$ 18	\$0.00
INDEPENDENT	1	_	3	=	0	\$ 84	\$0.00
FIRST PRESENTATION OF A MULTIPLE DEPENDENT CLAIM				\$280	\$0.00		
						TOTAL	\$0.00

(Rev. 09/30/02)

	Petition for () month(s) extension of time pursuant to 37 C.F.R. §§ 1.17 and 1.136(a). \$0.00 for the extension of time.
\boxtimes	No fee is required.
	Check(s) in the amount of \$0.00 is(are) enclosed.
	Please charge Deposit Account No. 02-2448 in the amount of \$0.00. This form is submitted in triplicate.
overprequi	If necessary, the Commissioner is hereby authorized in this, arrent, and future replies, to charge payment or credit any bayment to Deposit Account No. 02-2448 for any additional fees ared under 37 C.F.R. §§1.16 or 1.17; particularly, extensional fees.
	Respectfully submitted,
	BIRCH, STEWART, KOLASCH & BIRCH, LLP
	By / M Bird
•	Terrell C. Birch, #19,382
	P.O. Box 747 PMV/jdm Falls Church, VA 22040-0747 -0404P (703) 205-8000
Δttac	hment (s)





BOX AF REPLY UNDER 37 C.F.R. § 1.116 EXPEDITED PROCEDURE

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REPLY AFTER FINAL UNDER 37 C.F.R. § 1.116

BOX AF

Assistant Commissioner for Patents Washington, DC 20231

February 6, 2003

Sir:

In reply to the Office Action mailed November 7, 2002, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

IN THE CLAIMS:

Please amend the claims as follows:

1. (Twice Amended) A plasma processing method comprising:

supporting a substrate to be opposed to an electrode;

setting the plasma processing gas to pressure P(Torr) where P(Torr) satisfies the

following relationship

 $2x10^{-7}(Torr/Hz)xf(Hz) \le P(Torr) \le 500(Torr)$